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Specifications for pumps for UHV sputtering chamber

1. Magnetically levitated turbo molecular pump

- Inlet flange DN200CF
- Pumping speed:
- Nitrogen at least 1000 l/s
- Hydrogen at least 800 l/s
- Desired compression ratio:
 - Nitrogen at least 10⁸
 - Hydrogen at least 10⁵
- Ultimate Pressure in chamber must be in the order of 10⁻¹⁰ torr
- Maximum continuous outlet pressure 0.1 torr
- Maximum pump speed rating at least 35000 rpm
- Maximum inlet flange temperature 120°C
- Must be completely oil free
- Must be water cooled
- Must come with appropriate power cable with length at least 5 metres

2. Rotary vane pump (3 phase supply)

This pump will be used for backing the above turbo pump and for roughing the chamber.

- Minimum Displacement volume:
 - At 50Hz at least
 - At 60Hz at least
- Minimum speed:

- At 50Hz at least
- o At 60Hz at least
- Ultimate vacuum while roughing:
 - O Without gas ballast $-1*10^{-3}$ mbar
 - O With Gas ballast 2*10⁻² mbar
- Inlet connections NW25 flange
- Outlet connection Nozzle 15 mm external Ø removable from 3/4 in BSP tapped hole
- Maximum allowed pressure at outlet -0.5 bar
- Max inlet pressure for water vapour 30 mbar
- Minimum water vapour pumping rate 0.7 kg/hr
- Must be operational in the temperature range 15 to 40°C
- Nominal rotation speed:
 - o At 50Hz at least
 - At 60Hz at least
- Must include power cable, mist filter and spare oil for at least 1 refill